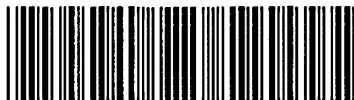


Search Notes

Application/Control No.

10/673,058

Examiner

Marissa J. Detschel

Applicant(s)/Patent under
Reexamination

HWANG ET AL.

Art Unit

2877

SEARCHED

Class	Subclass	Date	Examiner
356	72	9/22/2005	MJD
356	450	9/22/2005	MJD
356	511	9/22/2005	MJD
356	512	9/22/2005	MJD
356	73	9/22/2005	MJD
356	516	9/23/2005	MJD
356	496	9/23/2005	MJD
356	503	9/23/2005	MJD
356	504	9/23/2005	MJD
356	508	9/23/2005	MJD
356	498	9/23/2005	MJD

INTERFERENCE SEARCHED

Class	Subclass	Date	Examiner

**SEARCH NOTES
(INCLUDING SEARCH STRATEGY)**

	DATE	EXMR
EAST search all applicable areas under subclass 356/450 for devices with two light sources	9/23/2005	MJD
EAST search for tdi and frame adj capture or reference near mirror or interfer\$ and microscop\$ or fringe or phase	9/26/2005	MJD
EAST search for interfer\$ near microscop\$ and fringe and tilt or tilt near reference adj mirror and fringes	9/26/2005	MJD
EAST search for tilt near mirror and fringe or frame adj capture adj mode and fringe or wafer and fringe and magnif\$ or tdi	9/26/2005	MJD
EAST search for class 356 and microscop\$ and interfer\$ and tdi or wafer	9/27/2005	MJD
EAST search for interfer\$ near microscope and tilt or adjust near mirror or tdi	10/3/2005	MJD